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## THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicants : Yukio IDE et al.

Serial No. : 10/672,353

Group Art Unit 1742

Filed

: September 25, 2003

Examiner M.P. Alexander

For

: METHOD OF PRODUCING A SPUTTERING TARGET

## DECLARATION UNDER 37 C.F.R. \$1.132

We, Yukio IDE, Hiroko IWASAKI, Yoshiyuki KAGEYAMA, Yujiro KANEKO, Katsuyuki YAMADA, Michiaki SHINOTSUKA, Makoto HARIGAYA and Hiroshi DEGUCHI, declare that:

- 1. We are the joint applicants named in the above-identified application, and we are the joint inventors of the invention claimed in claim 33 of that application.
- 2. We are familiar with U.S. patent No. 5,882,493 ("the '493 patent"). Six of us (Hiroko IWASAKI, Yoshiyuki KAGEYAMA, Makoto HARIGAYA, Hiroshi DEGUCHI, Katsuyuki YAMADA, and Yukio IDE) were six of the eight joint applicants named in the application on which the '493 patent issued.
- 3. We jointly conceived the method of producing sputtering targets having the following specific compositions A and B:

	A (atomics)	B (atomica)
Ag	4.0	7.0
In	15.0	11.0
Te	25.0	22.0
Sb	56.0	60.0

by performing steps of mixing silver, indium and tellurium, heating the obtained mixture to a temperature above 600° so that the mixture is fused, rapidly cooling the substances of the mixture so that the resulting substances contain a chalcopyrite of AgInTe<sub>2</sub>, grinding the substances into particles, mixing the particles with silver, indium and tellurium with a simple substance of antimony, and sintering the mixture.

- 4. Insofar as the subject matter specified in numbered paragraph 3 above is suggested or described in Examples 1 and 3 (EX1 and EX3) in Table 1A at col. 9 of the '493 patent in conjunction with the disclosure e.g. at col. 4, lines 50-60, of the '493 patent, that subject matter was originally conceived by us and the description thereof is a description of subject matter that we conceived.
- 5. At the time that we conceived the subject matter specified in numbered paragraph 3 above, and at the time that the invention claimed in our above-identified application was made, we were employed by Ricoh Company, Ltd., assignee of the '493 patent and of the above-identified application.

We hereby declare that all statements made herein of our own knowledge are true and that all statements made on information and belief are believed to be true; and further that these statements were made with the knowledge that willful false statements and the

like so made are punishable by fine or imprisonment, or both, under Section 1001 of Title 18 of the United States Code and that such willful false statements may jeopardize the validity of the application or any patent issued thereon.

		// *
Date: .	2007. 2. 28	Yukio IDE
Date:		Hiroko IWASAKI
Date:	· .	Yoshiyuki KAGEYAMA
Date:		Yujiro KANEKO
Date:		Katsuyuki YAMADA
Date:		Michi <sup>‡</sup> ço SHINOTSUKA
Date:		Makoto HARIGAYA
D-45.	,	Hiroshi DEGUCHI



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## STATEMENT CONCERNING COMMON OWNERSHIP

1185 Avenue of the Americas New York, NY 10036 March 6, 2007

Commissioner for Patents P.O. Box 1450 Alexandria, VA 22313-1450

S I R:

I, the undersigned attorney of record in the above-identified application, hereby state that the above-identified application and U.S. patent No. 5,882,493 were, at the time the invention of claim 33 of the above-identified application was made, owned by, or subject to an obligation of assignment to, Ricoh Company, Ltd.

Respectfully,

Christopher C. Dunham

Reg. No. 22,031

Attorney for Applicants

Tel. (212) 278-0400